

Response under 37 C.F.R. 1.55
- Expedited Examining Procedure -
Examining Group 1763

BOX AF
Docket 83401RLO

AE
1100

Customer No. 01333

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Steven A. Van Slyke, et al

Group Art Unit: 1763

Examiner: Richard R. Bueker

THERMAL PHYSICAL VAPOR
DEPOSITION SOURCE FOR MAKING
AN ORGANIC LIGHT-EMITTING
DEVICE

I hereby certify that this correspondence is being
deposited today with the United States Postal
Service as first class mail in an envelope addressed
to Commissioner for Patents, Washington, D.C. 20231.

Paula West

Date

Serial No. US 09/996,415

Filed 28 November 2001

Commissioner for Patents
Washington, D.C. 20231

RECEIVED
SEP 30 2002
TC 1700

Transmitted herewith is an amendment in the above-identified application:

- ☒ No additional fee is required.
☐ The fee has been calculated as shown below:

	(Col. 1)		(Col. 2)	(Col. 3)	OTHER THAN A SMALL ENTITY	
	CLAIMS REMAINING AFTER AMENDMENT		* HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	18	MINUS	20	0	X 18	\$ 0
INDEP	2	MINUS	3	0	X 84	\$ 0
FIRST PRESENTATION OF MULTIPLE DEPENDENT CLAIM					+ 280	\$ 0
TOTAL						\$ 0

* The "Highest Number Previously Paid For" (Total or Independent) is the highest number found from the equivalent box in Col. 1 of a prior amendment or the number of claims originally filed.

☐ Please charge my Eastman Kodak Company Deposit Account No. 05-0225 in the amount of \$ 0.

A duplicate copy of this sheet is enclosed

☒ The Commissioner is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Eastman Kodak Company Deposit Account No. 05-0225

A duplicate copy of this sheet is enclosed

☒ Any additional filing fees required under 37 CFR 1.16.

☒ Any patent application processing fees under 37 CFR 1.17.
(For Extensions of Time and other Petitions to the Assistant Commissioner)

Raymond L. Owens/phw
Telephone: (585) 477-4653
Facsimile: (585) 477-4646

Attorney for Applicants
Registration No. 22,363



Response under 37 C.F.R. 1.116
- Expedited Examining Procedure -
Examining Group 1763

BOX AF
83401RLO

Customer No. 01333

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Steven A. Van Slyke, et al

THERMAL PHYSICAL VAPOR
DEPOSITION SOURCE FOR
MAKING AN ORGANIC LIGHT-
EMITTING DEVICE

Serial No. US 09/996,415

Filed 28 November 2001

5 Commissioner for Patents
Washington, D.C. 20231

Sir:

Group Art Unit: 1763

Examiner: Richard R. Bueker

I hereby certify that this correspondence is being deposited today with the
United States Postal Service as first class mail in an envelope addressed to
Commissioner for Patents, Washington, D.C. 20231.

Paula West

Date

RECEIVED

SEP 30 2002

TC 1700

H4ANE
10/11/02
MW

10

RESPONSE UNDER 37 CFR 1.116

In response to the Office Action mailed July 8, 2002, please amend
the above-identified application as follows, without prejudice.

In the Claims:

15

Please amend Claim 1 as set forth below:

1. (once amended) A thermal physical vapor deposition
source for vaporizing solid organic materials and applying a vaporized organic
material as a layer onto a surface of a structure in a chamber at reduced pressure in
forming an organic light-emitting device (OLED), comprising:

20

- a) a bias heater defined by side walls and a bottom wall, the
side walls having a height dimension H_B ;
- b) an electrically insulative container disposed in the bias
heater, the container receiving solid organic material which can be vaporized, the
container defined by side walls and a bottom wall, and the container side walls